

PROJECT EVALUATION

FABRICATION AND TESTING OF

WS2 BASED PHOTODETECTOR

***SUBMITTED BY***

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**INDIAN INSTITUTE OF INFORMATION TECHNOLOGY**

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**Micro Sensors and Actuators**

## **PROJECT TITLE:**

Fabrication and Testing of metal disulfide WS<sub>2</sub> based optical sensor

## **ABSTRACT:**

In this project it is observed that sensitive towards 450nm compared to 532nm and in dark. Responsivity of this fabricated device at wavelength 450nm is 2.66 mA/W. detectivity is of 15847.45 jones. And analysed the rise and fall of the current vs time graph.

## **INTRODUCTION:**

Photodetectors, converting incident light into electric signals, are of tremendous interest due to their applications in industry and military, such as biochemical analysis, industrial automatic control, missile warning and so on. Photodetectors can be categorized into the broadband and the selective photodetectors, corresponding to wide-spectrum and spectrally distinctive photoresponse. Compared to the photodetectors with the relatively narrow response, the broadband photodetectors have great potential applications for ultraviolet–visible-infrared (UV–vis-IR) light communication, memory storage, and wide spectral switch in a single optoelectronic device system. Recently, two-dimensional (2D) materials have emerged as an ideal platform for realizing a variety of optoelectronic devices due to their unique properties. Among these 2D materials, WS<sub>2</sub> has been intensively studied in photodetection applications. For example, Yao et al. first demonstrated a multilayer WS<sub>2</sub> film based photodetector, which exhibits good photoresponse properties in terms of a high responsivity<sup>[1]</sup>. Semiconducting heterostructures, which are formed by assembling two disparate semiconductors with different lattice structures, electronic properties, or chemical compositions lay the foundation of modern electronics<sup>[4]</sup>. Upon the construction of the heterostructures, bending or hybridization of the electronic band structures of both the two components occurs, leading to the charge transfer at the interface<sup>[4]</sup>.

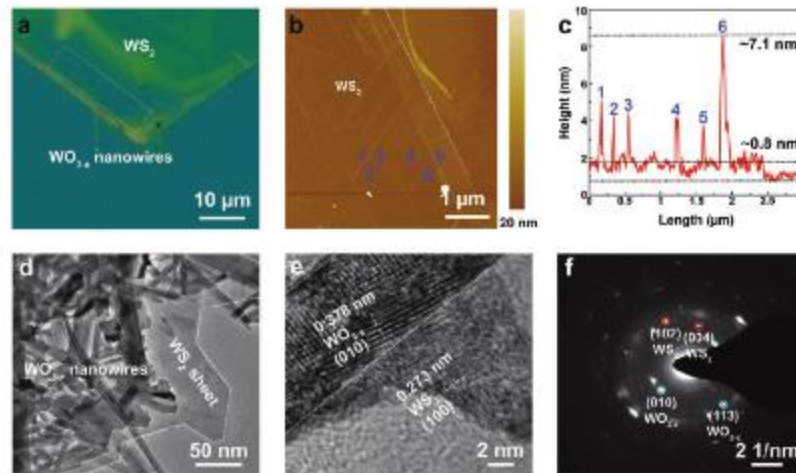


Figure 1. a,b) Optical image and surface morphology of  $\text{WO}_{3-x}/\text{WS}_2$  vdW heterostructure. c) Corresponding height profile. Three dash lines are corresponding to  $\text{WO}_{3-x}$ ,  $\text{WS}_2$ , and substrate, respectively. d) Low-resolution TEM image of  $\text{WO}_{3-x}/\text{WS}_2$  vdW heterostructure, in which  $\text{WO}_{3-x}$  nanowires are uniformly stacked on  $\text{WS}_2$  sheet. e) HRTEM of heterostructure. White dash lines indicate interface. f) Corresponding SAED of heterostructure.

Fig 1 optical image of  $\text{WS}_2$

Layered transition metal dichalcogenides (TMDCs) (e.g.  $\text{WS}_2$  and  $\text{MoS}_2$ ), hold high carrier mobility, a sizable band gap of 1–2 eV, and strong light-matter interaction, which make these materials very prospective for optoelectronic devices. The weak van der Waals (vdW) bonds among the adjacent layers allow bulk TMDCs crystals to be effectively exfoliated, enabling direct deposition of such layered crystals by direct abrasion against the substrate. In addition, the high surface roughness and porous nature of cellulose fibers not only aid the adhesion of the deposited material but also

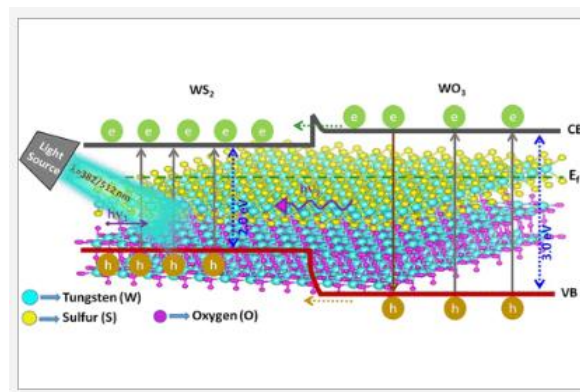


Fig2 [3]. PHOTO DETECTIVITY OF THE  $\text{WS}_2/\text{WO}_3$

provides a larger photoactive area for optoelectronic devices as compared to

conventional planar substrates<sup>[2]</sup>. a strategic development of WS<sub>2</sub>/WO<sub>3</sub> heterostructures by sputtering and chemical vapor deposition techniques to fabricate a metal–semiconductor–metal planar-structured Ag/WS<sub>2</sub>/WO<sub>3</sub>/Ag photodetector device with interdigitated Ag electrodes. A comparative study has been made based on the photodetector performance between the WS<sub>2</sub>/WO<sub>3</sub> heterostructure and pristine WO<sub>3</sub> and WS<sub>2</sub> thin-film-based devices. WO<sub>3</sub> and also reduces the recombination losses by absorbing the emitted radiation with WO<sub>3</sub><sup>[2]</sup> Recently, the optoelectronic properties of vdW semiconducting heterostructures reach a new height by replacing one of the TMDs components with the transition metal oxides (TMOs). Apparently, such a replacement, particularly of the top component in the heterostructure, greatly enhances the long-term stability of the device as ultra-thin TMDs exhibit slow surface oxidation upon exposure in the ambient air environment. More importantly, oxygen vacancies, commonly existing in nanostructured TMOs, could introduce optically-active gap states for enhancing the light absorption and the production of photogenerated carriers. However, the single-step synthesis of ultrathin TMOs/TMDs vdW heterostructures is challenging given the balance of oxidizing and reducing atmospheres for the growth of TMOs and TMDs, respectively. The quality of the heterostructure interface is critical here as any crystal distortions or defects can interfere with the charge transfer behavior significantly, hence leading to the strong demand of heterostructures governed by the van der Waals(vdW) force<sup>[4]</sup>. we utilized the quantity-driven discrepancy of S reaction with precursors to realize the single-step CVD synthesis of a WO<sub>3-x</sub>/WS<sub>2</sub> vdW semiconducting heterostructure. Particularly, S acts as a sulfication agent to convert the precursor WO<sub>3</sub> into WS<sub>2</sub> in the presence of an excessive amount of S<sup>[4]</sup>.

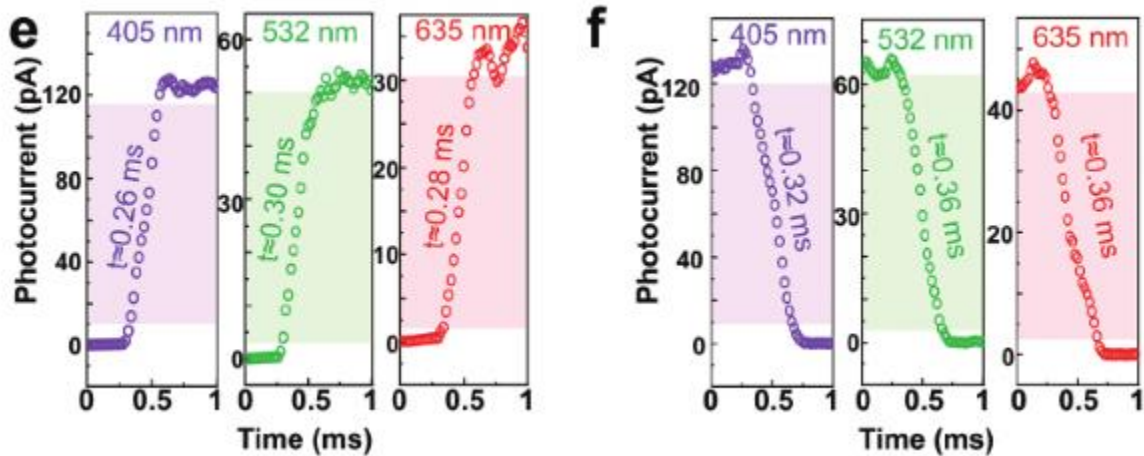


Fig 3 Time-resolved photocurrent with rise and fall time under different excitation wavelengths.

## PROBLEM STATEMENT:

The main objective of this project is to develop photodetector/optical sensor devices. Our second objective is finding the Time-resolved photocurrent with rise and fall time under different excitation wavelengths. finding the responsivity and detectivity for different wavelengths.

## METHODOLOGY AND NEW FINDINGS:

### For deposition of the Tungsten:

Equipment and Materials:

- Sputtering system (e.g., magnetron sputtering system)
- Tungsten target
- Substrate (e.g., silicon, glass, quartz)
- Argon (Ar) gas
- Vacuum pump
- RF or DC power supply
- Cleanroom environment (optional, depending on application)

Procedure:

- Substrate Preparation
- Load the Substrate into the Sputtering System:
- Pump Down the Chamber:
- Sputtering Process:

- Deposition onto Substrate:

### **For deposition of the Tungsten tri oxide:**

- Equipment and Materials:
  - Tungsten wafer or substrate
  - Oxidation furnace or system(cvd)
  - Oxygen (O<sub>2</sub>) gas
  - Thermocouple or temperature controller
  - Cleanroom environment (optional, depending on application)

#### **Procedure:**

- Preparation of Tungsten Wafer:
- Load the Wafer into the Oxidation System(cvd)
- Establish Oxidizing Atmosphere:
- Heating and Oxidation:

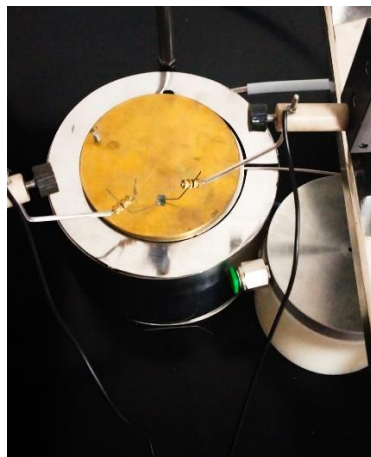
### **For deposition of the Tungsten tri oxide:**

- Equipment and Materials:
  - Oxidized tungsten wafer
  - CVD furnace or system(cvd)
  - Sulphur powder is kept in furnance
  - Thermocouple or temperature controller
  - Cleanroom environment (optional, depending on application)

#### **Procedure:**

- Preparation of Tungsten Wafer:
- Load the Wafer into the Oxidation System(cvd)
- Heating and sulphurisation

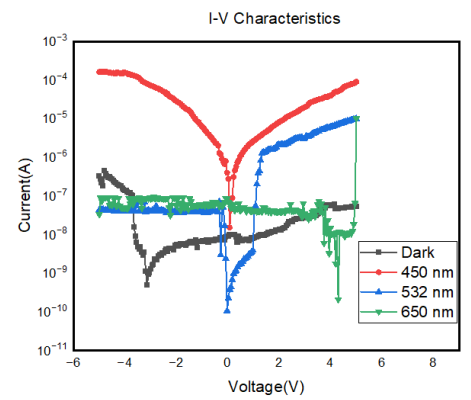
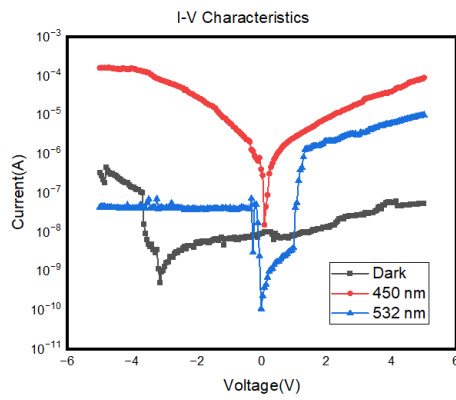
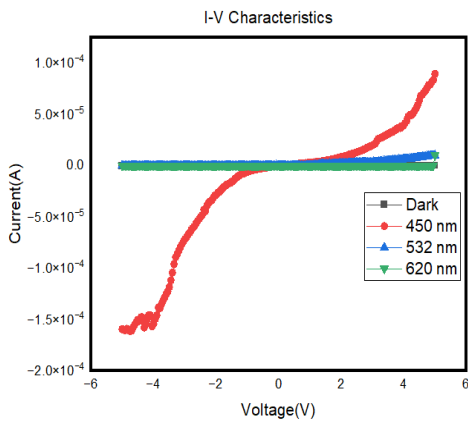
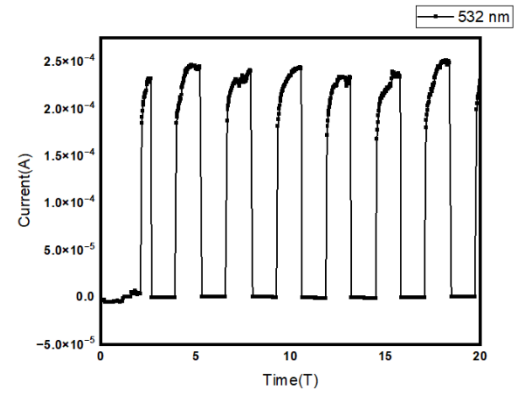
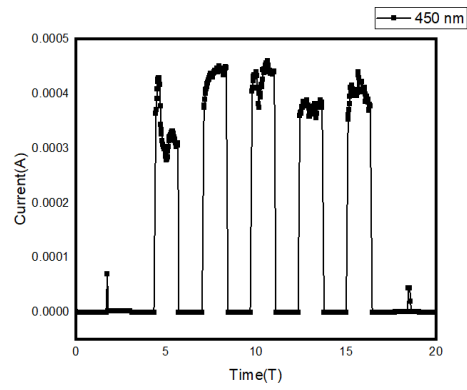
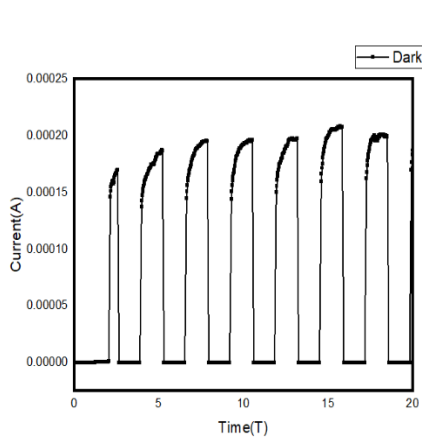
### **EXPERIMENTAL DETAILS:**



**Fig 4 probing for taking measurements**

- p/Si<100>
- deposition of tungsten using sputtering for 30 mins
- oxidation of the substrate using CVD at 500°C-550°C for nearly 2 hours
- sulphurisation of the substrate using CVD at 750°C.

## RESULT AND DISCUSSION:



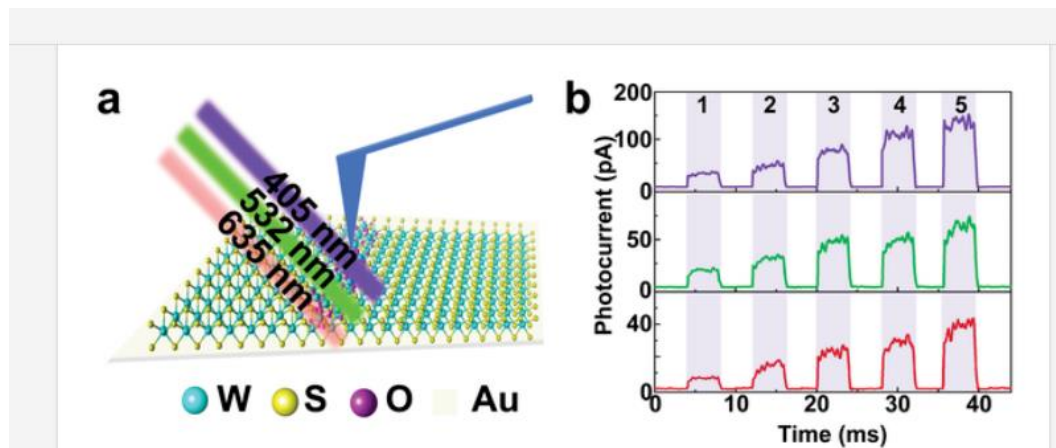


Fig 5 [3] graph of current versus time

$$\text{Photoresponsivity}(R) = \frac{I_{ph}}{P_{in} \times A} \quad (1)$$

$$\text{Detectivity}(D) = \frac{R \times \sqrt{A}}{\sqrt{2eI_d}} \quad (2)$$

$$\text{EQE}(\%) = R \times \frac{hc}{e\lambda} \quad (3)$$

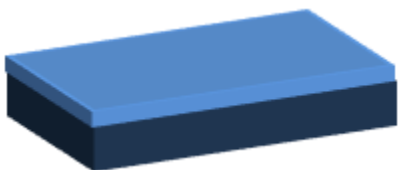
## MECHANISM WITH DIAGRAM:

1.



Silicon (si) substrates, don't hold the substrate with the bare hands. Handle it with care.

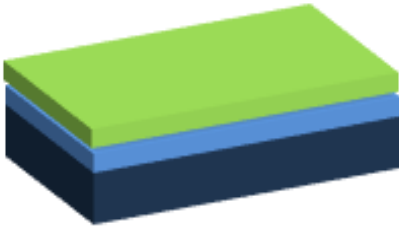
2.



SiO<sub>2</sub> is spin coated on the double sides of the silicon substrate.

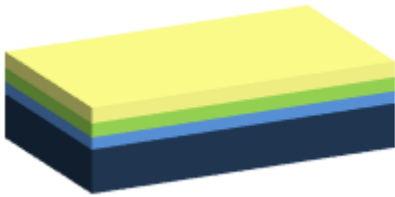


3.



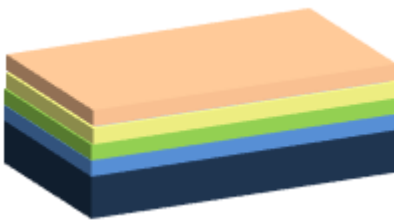
A thin film of Tungsten is deposited on the Si substrate using DC magnetron Sputtering

4.



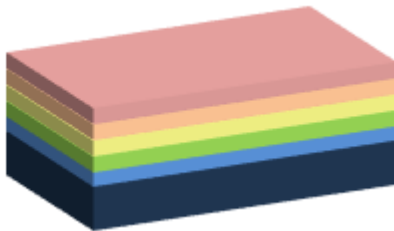
Oxidation of the tungsten  
Using CVD (chemical vapor deposition)

5.



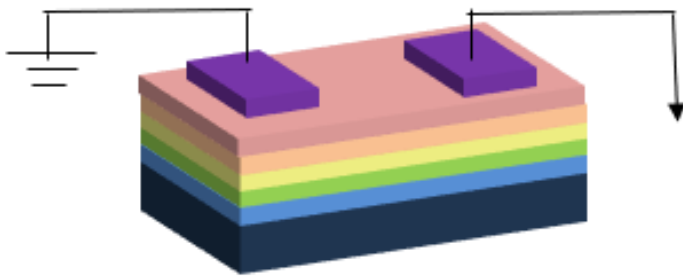
After oxidation of wafer  
 $2W + 3O_2 \rightarrow 2WO_3$

6.



$2WO_3 + 4S \rightarrow 2WS_2 + 3O_2$   
Sulphurisation of  $WO_3$

7.



Probing to the two of SMU(source measure unit).

### **APPLICATIONS:**

WS2 sensing at 450 nm, 532 nm, and 652 nm can be applied in colorimetry for accurate color detection and in environmental monitoring for analyzing specific light wavelengths related to pollutants or contaminants.

### **CHALLENGES FACED:**

Handling the sulfur during the fabrication and during testing the maintaining the surrounding environment silently. carefully Probe the device while doing the measurement.

### **CONTRIBUTION OF INDIVIDUAL TEAM MATES:**

Divya.M- generated 3 origin file from the measured values. searched [1] and [3] reference paper. Calculated responsivity.

Jahnavi.O- measuring and taking values from the device, generated one origin file from the measured values and searched [4] and [5] reference paper. Contributed in making report.

Sruthi.N-generated 2 origin file, searched [1] and [6] reference paper. Contributed in making report. Calculated detectivity.

## **FUTURE WORK:**

In the future we are going to fabricate this device to increase the responsivity of this device and photo detectivity

## **CONCLUSIONS:**

In summary we tested fabricated WS<sub>2</sub> using sputtering and CVD followed by Ag contacts. This fabricated WS<sub>2</sub> is useful in measuring the specific wave length of the light detecting the specific wavelength and environmental pollution

## **REFERENCES:**

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[2]. Solvent-free fabrication of broadband WS<sub>2</sub> photodetectors on paper Wenliang Zhang<sup>1</sup>, Onur Çakıroğlu<sup>1</sup>, Abdullah Al-Enizi<sup>2</sup>, Ayman Nafady<sup>2</sup>, Xuetao Gan<sup>3</sup>, Xiaohua Ma<sup>4</sup>, Sruthi Kuriakose<sup>1</sup>, Yong Xie<sup>1,4\*</sup> and Andres Castellanos-Gomez<sup>1</sup>

[3] WS<sub>2</sub>/WO<sub>3</sub> Heterostructure-Based Photodetectors on SiO<sub>2</sub>/Si for Future Optoelectronics  
P.V. Karthik Yadav And Y. Ashok Kumar Reddy\*

[4] A Single-Step-Grown Semiconducting vdW Heterostructure of Tungsten Oxide–Sulfide for High-Performance Photodetection Guanyu Chen, Xinyi Hu, Mingwei Gu, Hao Wu, Keyu Chen, Hao Yu, Baiyu Ren, Zhong Li, Yange Luan, Tao Tang, Yinfen Cheng, Haibo Huang,\* Liguao Chen,\* Bao Yue Zhang,\* and Jian Zhen Ou\*

[5] Thermal Effects Associated with the Raman Spectroscopy of  $\text{WO}_3$  Gas-Sensor Materials

Raul F. Garcia-Sanchez<sup>†</sup>, Tariq Ahmido<sup>‡</sup>, Daniel Casimir<sup>†</sup>, Shankar Baliga<sup>§</sup> and Prabhakar Misra<sup>\*†</sup>

[6] High-Efficiency Photodetector Based On CVD-Grown  $\text{WS}_2$  Monolayer Rakesh K. Prasad<sup>1</sup>, Koushik

Ghosh<sup>2</sup>, P. K. Giri<sup>2</sup>, Dai-Sik Kim<sup>3</sup>, Dilip K. Singh<sup>1\*</sup> <sup>1</sup> Department of Physics, Birla Institute of

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